**k-Space Associates, Inc.**

NEW!

MULTI-WAFER TEMPERATURE AND FULL PLATEN MAPPING!

By utilizing the **kSA BandiT** band-edge based temperature monitoring system along with sophisticated rotational synchronization techniques, full platen/susceptor temperature mapping and analysis of all wafers in real-time is now possible during MBE and MOCVD growth!

The latest kSA BandiT multi-wafer temperature monitoring software, combined with optional automated servo motor-controlled detector scanning, yields a powerful technique for obtaining full wafer and platen temperature mapping in real-time. The system is the only monitoring technique that can provide real-time 2-dimensional temperature information of all wafers during growth. Thermal uniformity profiles can now be monitored and adjusted via typical multiple filament heating zones used on today's production MBE systems. The mapping system is also available for single wafer MBE and MOCVD systems where full wafer temperature uniformity measurements are desired.

Multi-wafer and/or mapping configurations are now available for most commercial single and multi-wafer systems, with the following features:

- **Standard viewport integration**

- **User-defined temperature marker locations based on platen/susceptor geometry and wafer configuration**

- **Fully automated operation**

- **Engineer and operator level interface**

- **Single point or area average**

- **Standard designs now available for all commercial MBE and MOCVD systems**
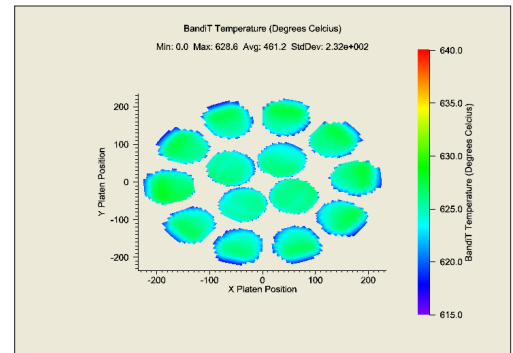
Real-time kSA BandiT temperature map of 14 x 4" platen on Veeco GEN2000 MBE system showing spatially-resolved, full wafer temperature during growth.

Screen shot of kSA BandiT MW software interface.

Contact k-Space for more information!

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